

Title (en)

ATOMIC LAYER DEPOSITION SYSTEM AND METHOD

Title (de)

VORRICHTUNG UND VERFAHREN ZUR ABSCHIEDUNG VON ATOMAREN SCHICHTEN

Title (fr)

SYSTEME ET PROCEDE DE DEPOT EN COUCHES ATOMIQUES

Publication

EP 1436443 A1 20040714 (EN)

Application

EP 02731204 A 20020327

Priority

- US 0209999 W 20020327
- US 28162801 P 20010405
- US 90208001 A 20010709
- US 97086701 A 20011003
- US 99949901 A 20011024
- US 99953201 A 20011024
- US 99963601 A 20011024
- US 38201 A 20011024
- US 82501 A 20011024
- US 448801 A 20011024
- US 2759201 A 20011219

IPC 1-7

C23C 16/00

IPC 8 full level

C23C 16/448 (2006.01); **C23C 16/455** (2006.01); **C23C 16/458** (2006.01); **C23C 16/515** (2006.01); **H01J 37/32** (2006.01); **C23C 16/44** (2006.01)

CPC (source: EP)

C23C 16/4486 (2013.01); **C23C 16/45508** (2013.01); **C23C 16/45536** (2013.01); **C23C 16/45544** (2013.01); **C23C 16/45565** (2013.01); **C23C 16/4586** (2013.01); **C23C 16/515** (2013.01); **H01J 37/3244** (2013.01); **H01J 37/32449** (2013.01); **H01J 37/32862** (2013.01)

Designated contracting state (EPC)

AT BE CH CY DE DK ES FI FR GB GR IE IT LI LU MC NL PT SE TR

DOCDB simple family (publication)

WO 02081771 A2 20021017; EP 1436443 A1 20040714

DOCDB simple family (application)

US 0209999 W 20020327; EP 02731204 A 20020327